

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| | | |
|-------------------|---|---|
| Applicant | : | Shimomura, et al. |
| Int'l Appl. No. | : | PCT/JP2004/015480 |
| Int'l Filing Date | : | October 20, 2004 |
| For | : | POLISHING PAD AND SEMICONDUCTOR DEVICE MANUFACTURING METHOD |
| Examiner | : | Unknown |
| Group Art Unit | : | Unknown |

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

Prior to calculation of the number of claims, please amend the present application.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Remarks/Arguments begin on page 6 of this paper.